

EB_Profiler, v2.2

EB_Profiler, v2.2 is a LabVIEW program which uses computed tomography to determine the power distribution in the beams of electron beam welders. It requires that the National Instruments LabVIEW Run-Time Engine be installed. The program takes in beam profile data from a data acquisition device or from a data file. Beam parameters necessary for calculations are entered by the user or automatically extracted from header information in the data file. The result is a two-dimensional reconstruction of the power distribution in the beam.

References

1. A. T. Teruya, J. W. Elmer and D. W. O'Brien(1991) , A System for the Tomographic Determination of the Power Distribution in Electron Beams," The Laser and Electron Beam in Welding, Cutting, and Surface Treatment State-of-the-Art 1991, Bakish Materials Corporation, 125

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